



# Design and Analysis of 3D Capacitive Accelerometer for Automotive Applications



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# Objective

- Accelerometers which detect rapid collisions.
- 3D Capacitive accelerometers which are less prone to noise and temperature variations.
- Checking out maximum stress device withstands.



# Air bag deployment



- Vehicle safety device
- Airbag Control Unit(ACU)
- Accelerometers as inertia sensors in ACU

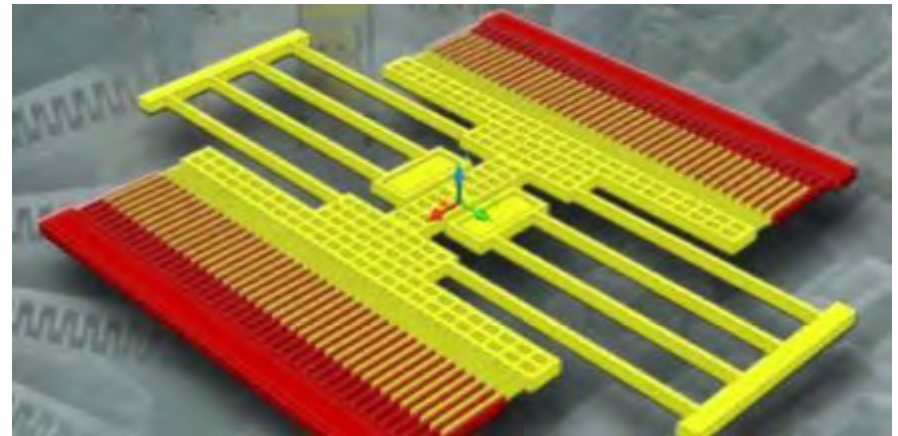
The driver and passenger front airbags, after having been deployed, in a Peugeot 306 car

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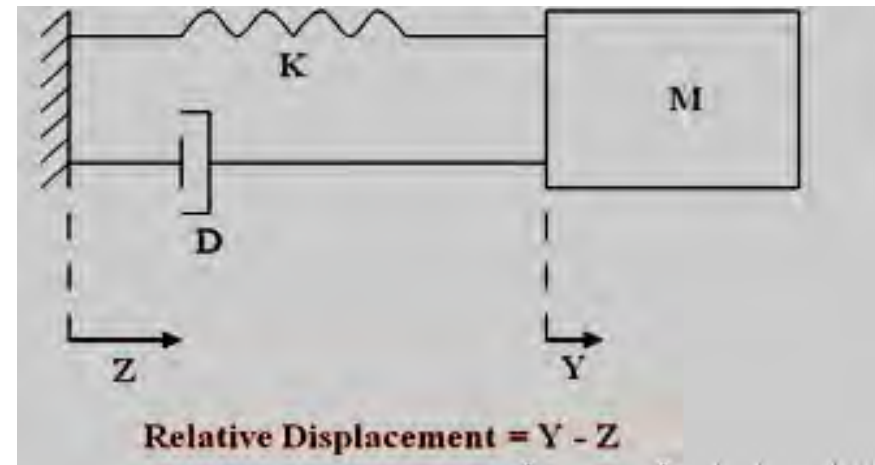
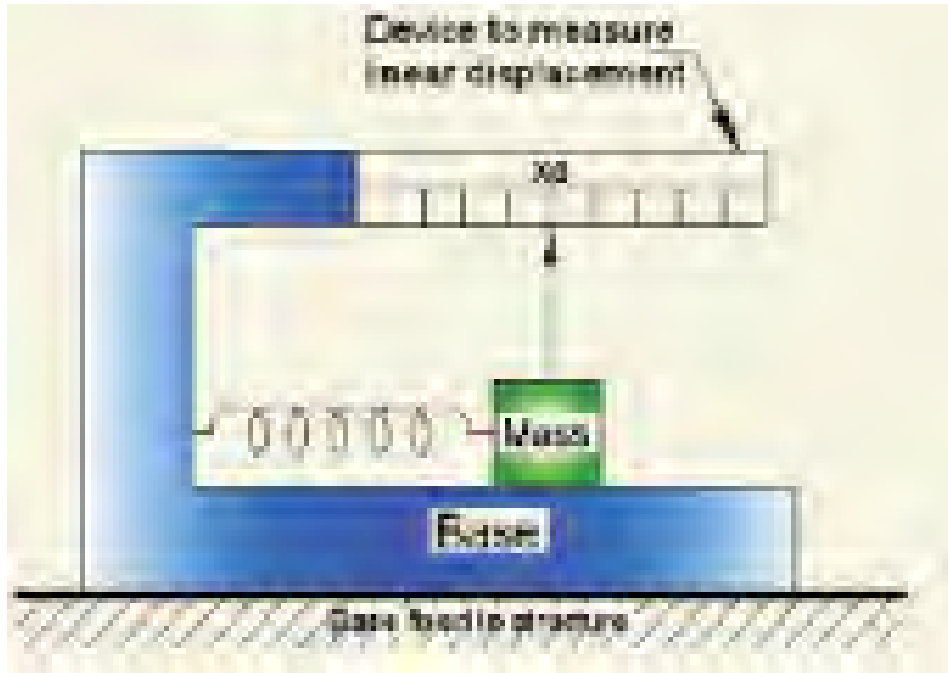


# Accelerometers

- An accelerometer thus measures **weight per unit of (test) mass**, a quantity also known as specific force , or g-force..
- Measuring is basically done by converting a mechanical signal in form of strain into an electrical signal



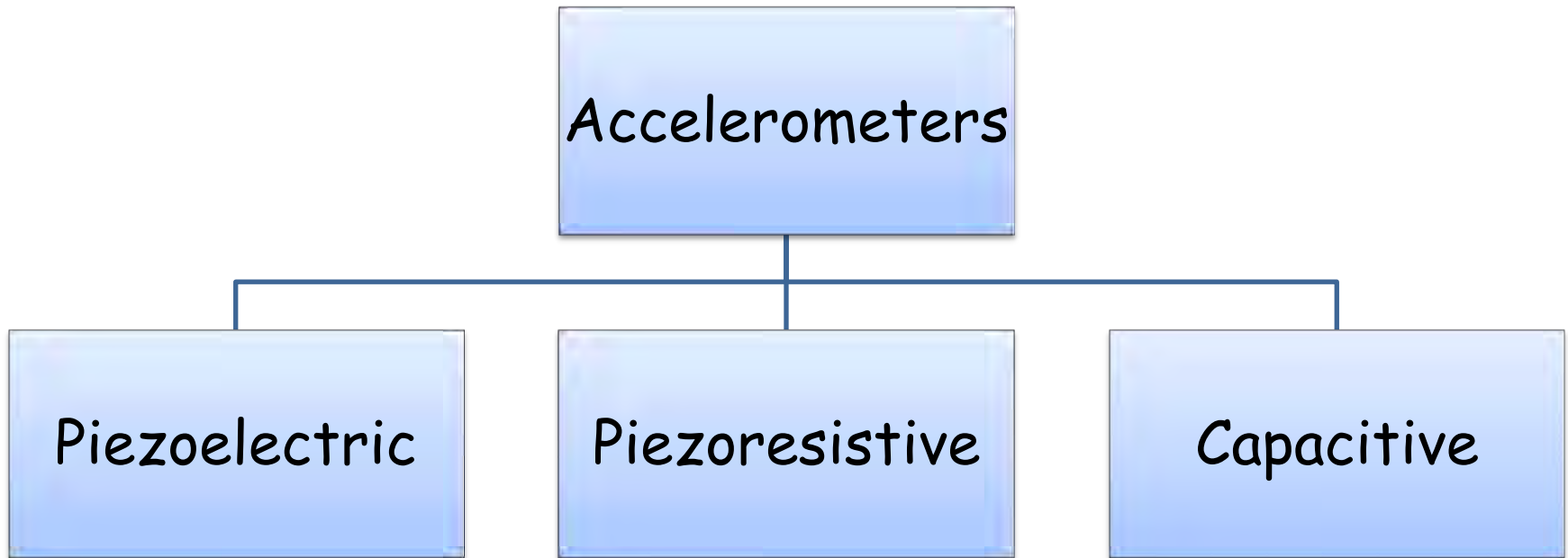
# Structure



Damped mass spring system



# Types of accelerometers



# Why Capacitive accelerometers?

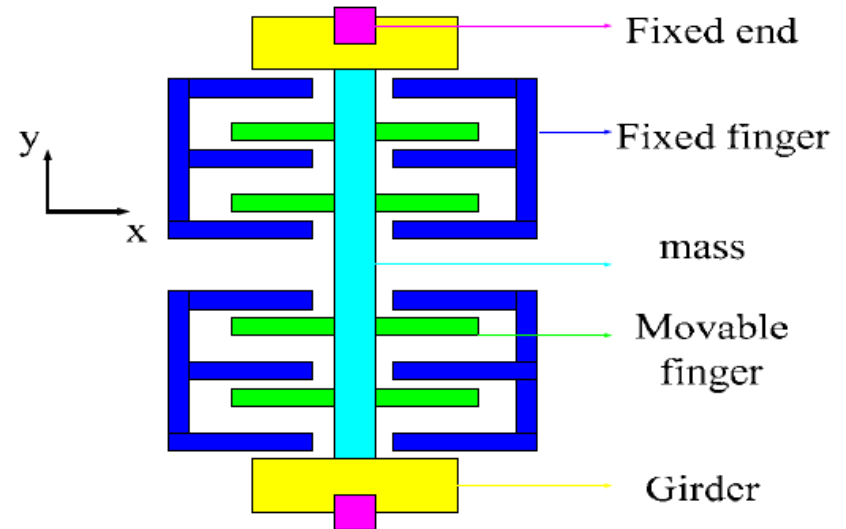
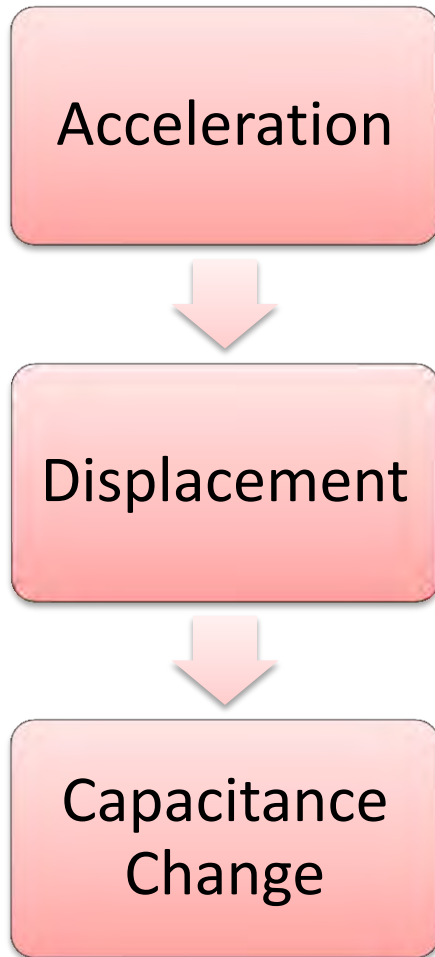
- Higher sensitivity
- Lower temperature coefficients.
- Less Prone to noise
- Low power consumption
- Excellent Stability



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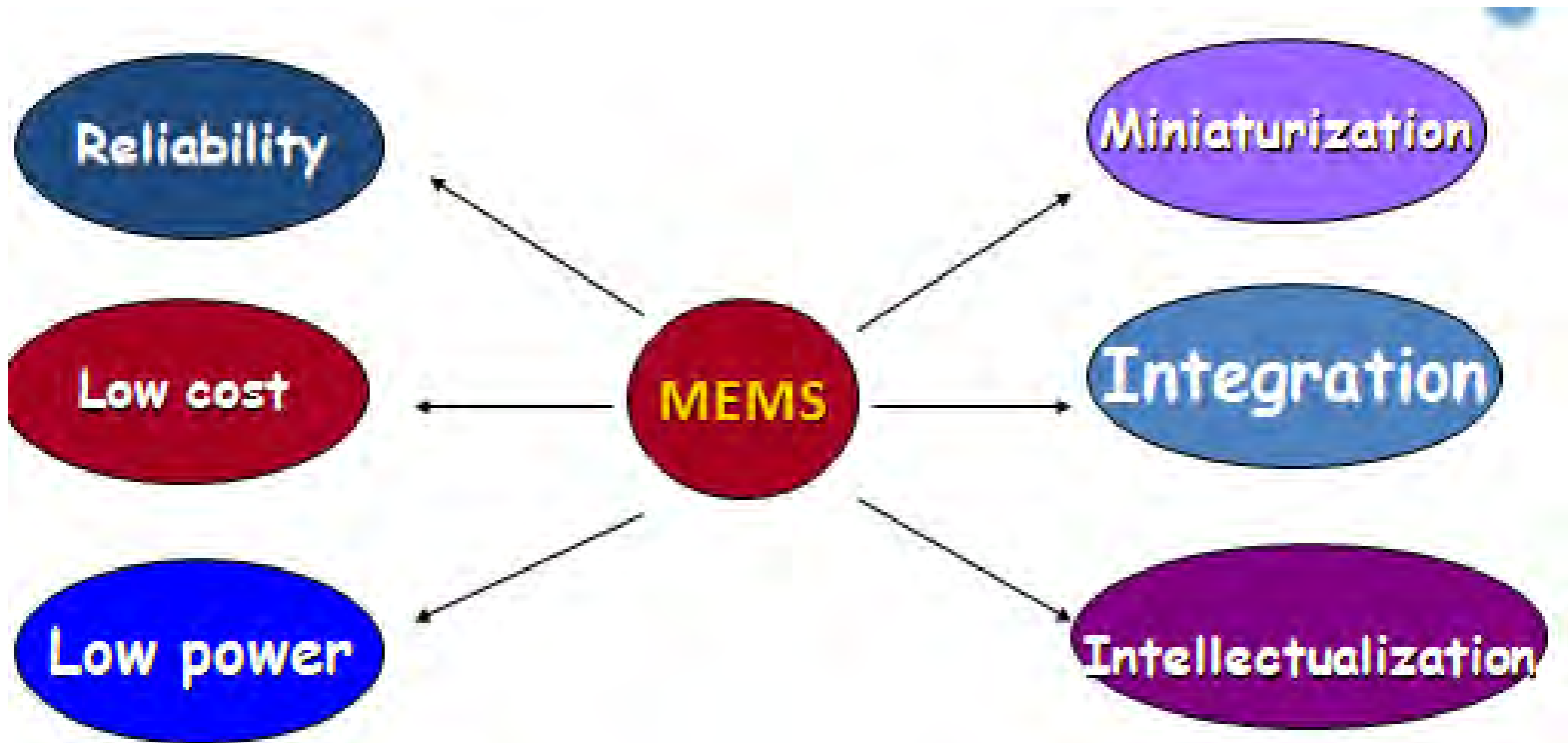


# Capacitive accelerometer

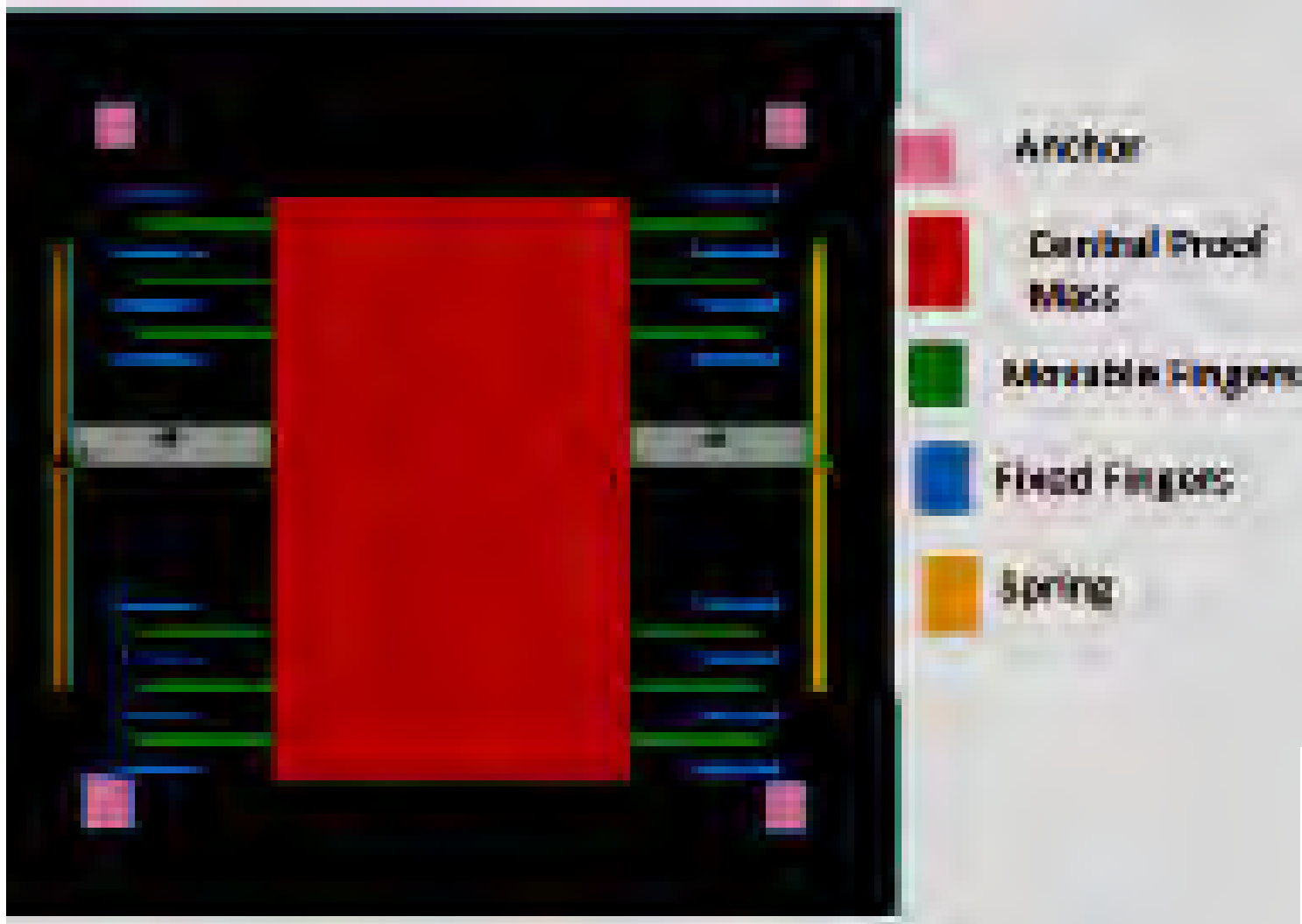




# Why MEMS accelerometers?

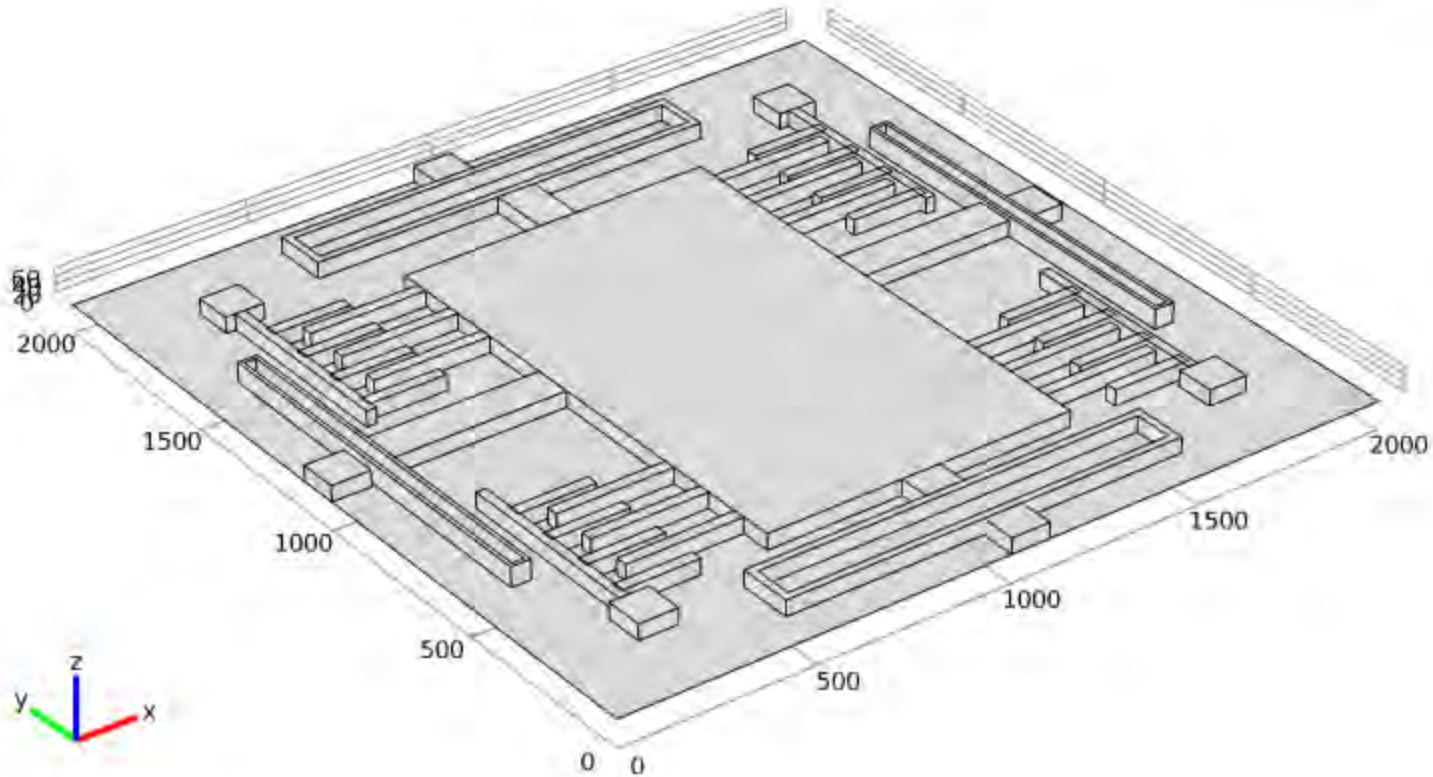


# Proposed Model





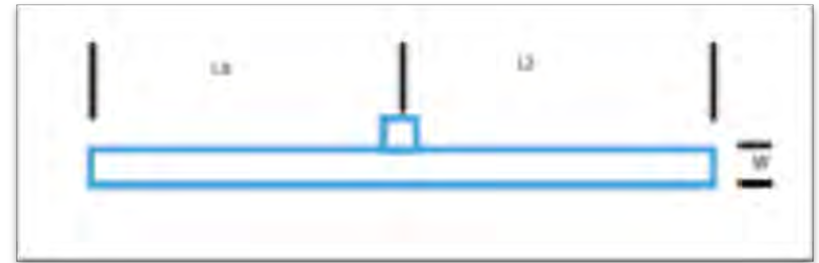
# Schematic view of 3D model



# Design Parameters

- Spring Constant

$$K = \left(\frac{\pi^4}{6}\right) \left[ \frac{EWH^3}{(2L_1)^3 + (2L_2)^3} \right]$$



Folded spring structure

- Mass

$$m = \rho V$$

- Reasonant frequency

$$\omega_0 = 2\pi f = \sqrt{\frac{K}{m}} \text{ or, } m = \frac{K}{\omega_0^2}$$



# Design Parameters

S.No	Parameter	Value
1	Spring constant (K) 2 spring	13.5829 N/m
	Spring constant (K) 4 spring	54.3364 N/m
2	Mass	$12.5605 \times 10^{-17}$ Kg

## Mass

Mass of central proof mass=  $9.69 \times 10^{-17}$  Kg

Mass of fixed and movable fingers =  
 $2.8705 \times 10^{-17}$  Kg

Total mass=  $12.5605 \times 10^{-17}$  Kg

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## Spring Constant

$E = 131 \times 10^9$  Pa for silicon

$W = 100$  nm

$H = 40$  nm

$L1 = L2 = 500$  nm



# Measurement Parameters

Capacitance

$$C = \epsilon A/d$$

Voltage output

$$V_{out} = \frac{C_1 - C_2}{C_1 + C_2} \times V_s$$

$$V_{out} = \left( \frac{\Delta x}{d} \right) V_s$$

$$\Delta x = ma/k$$

Where

$\Delta x$

is displacement,  $V_s$  is input voltage,  $d$  is original gap between electrodes.



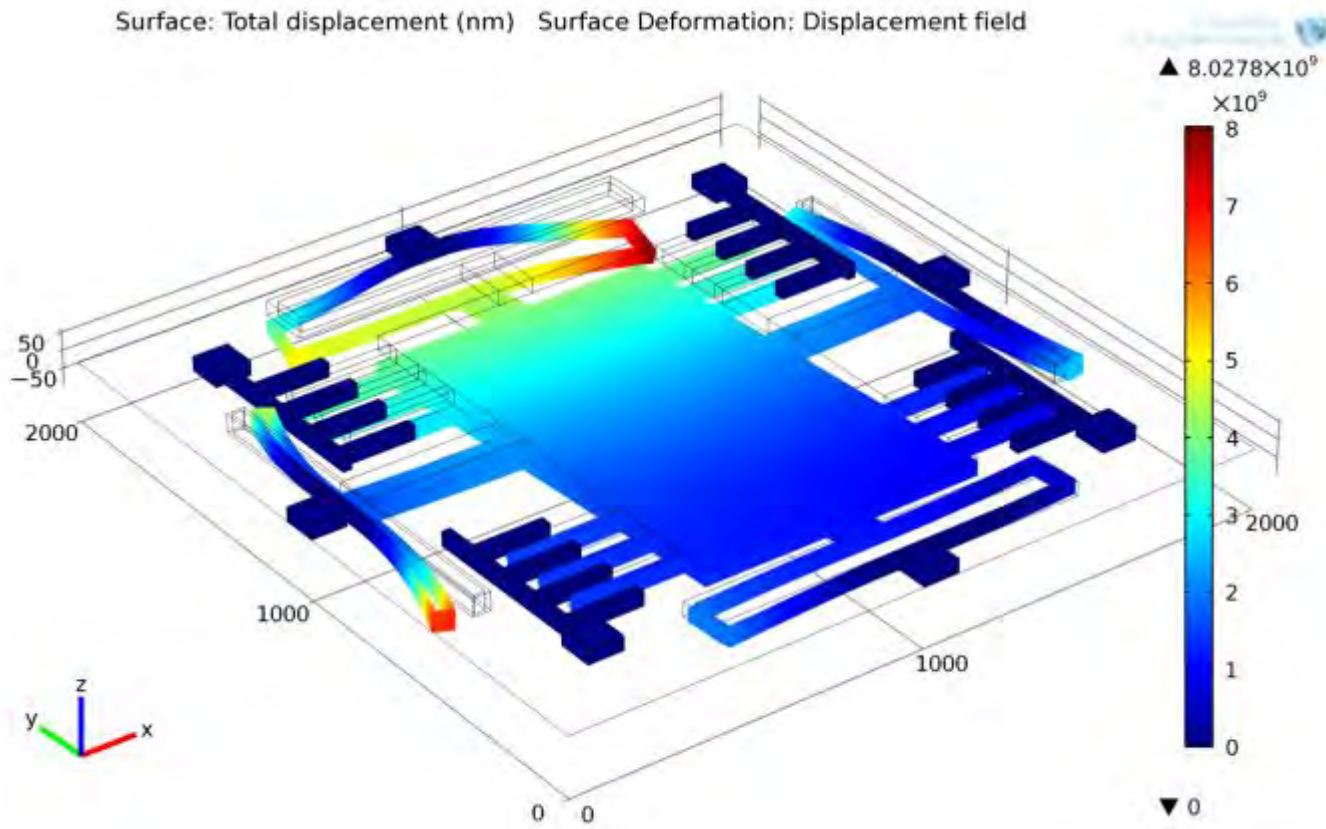


# Simulation

- **Software used** : COMSOL Multiphysics 4.1
- **Material**: Polysilicon
- **Physics**: Electrostatics & Solid mechanics
- **Mesh** : Free Tetrahedral

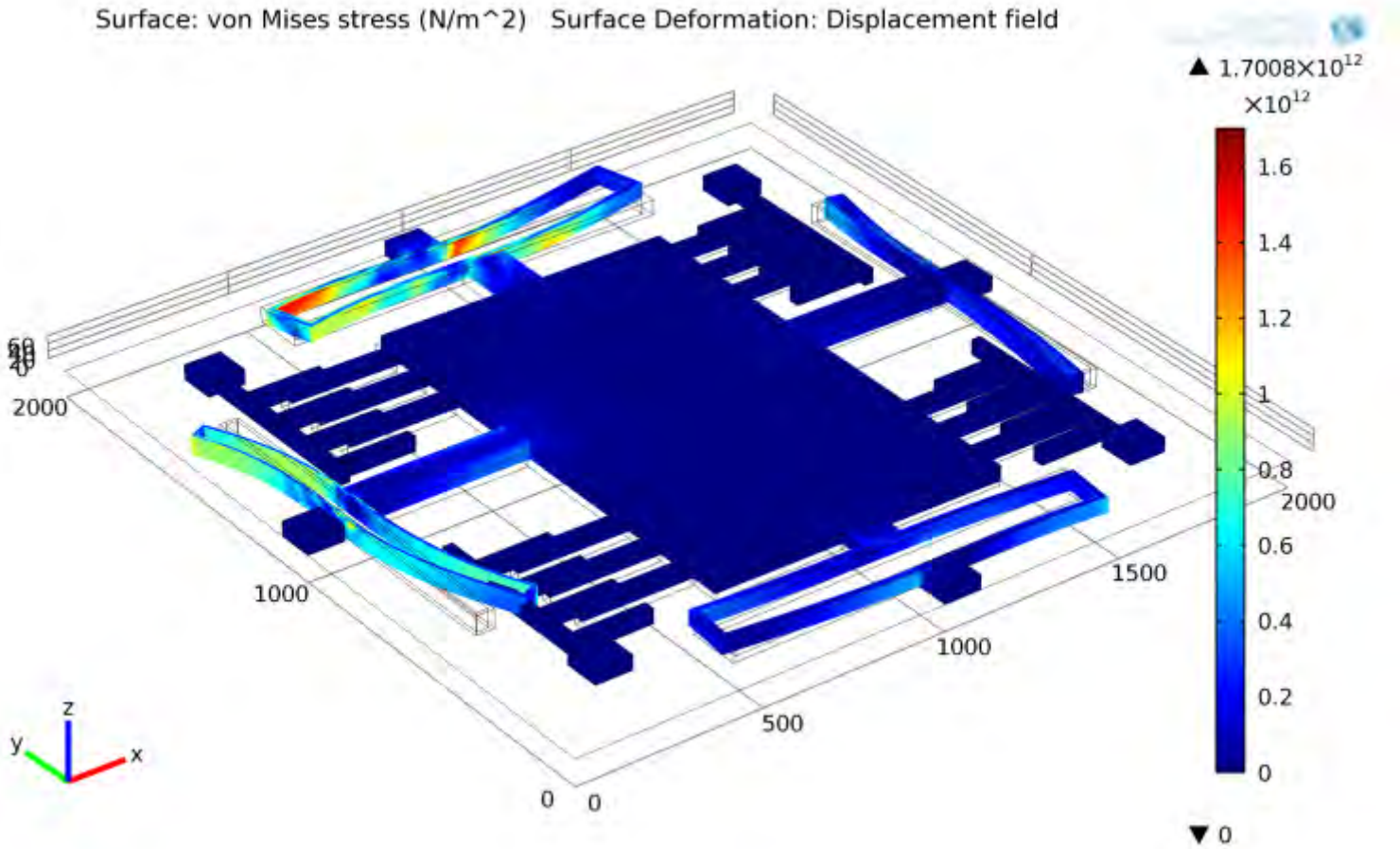


# Simulation Results

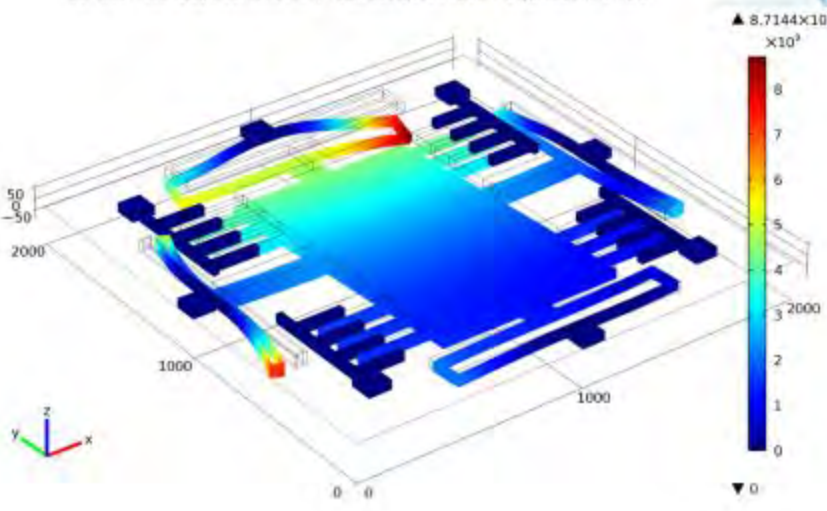




# Maximum Stress device withstands.....

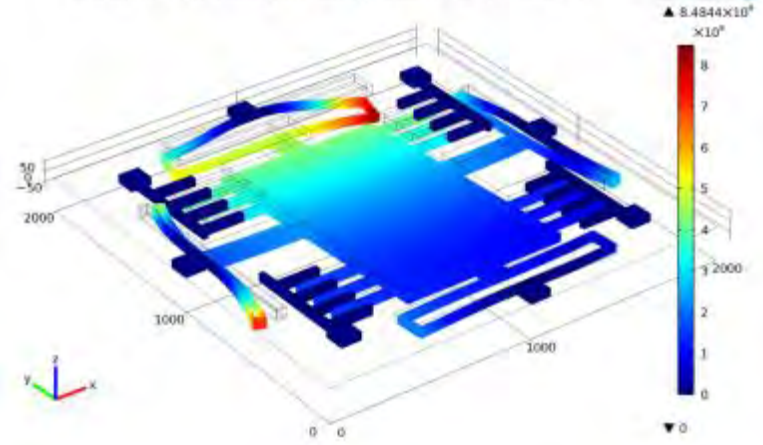


Surface: Total displacement (nm) Surface Deformation: Displacement field



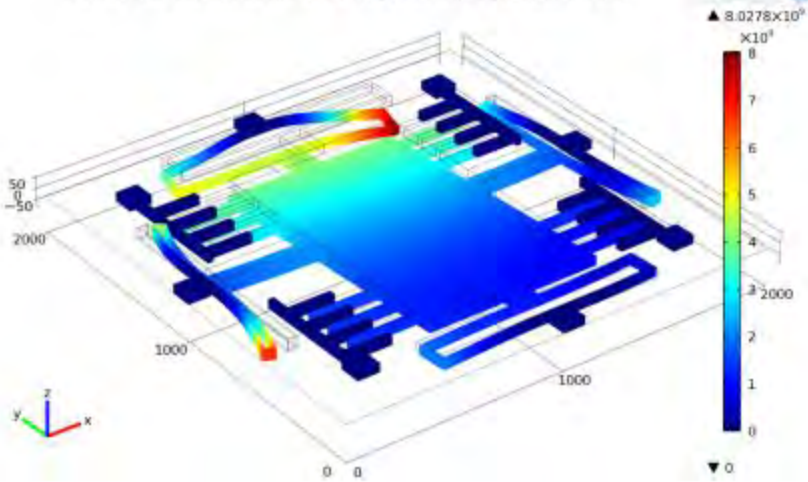
Acceleration: 25g

Surface: Total displacement (nm) Surface Deformation: Displacement field



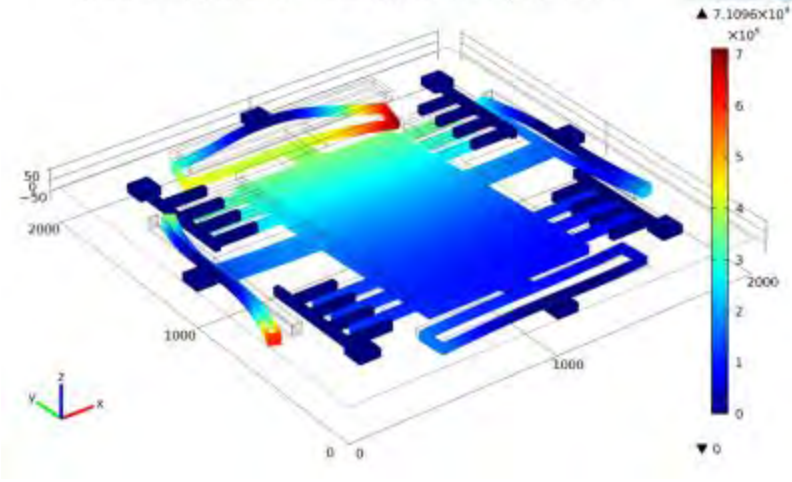
Acceleration: 50g

Surface: Total displacement (nm) Surface Deformation: Displacement field



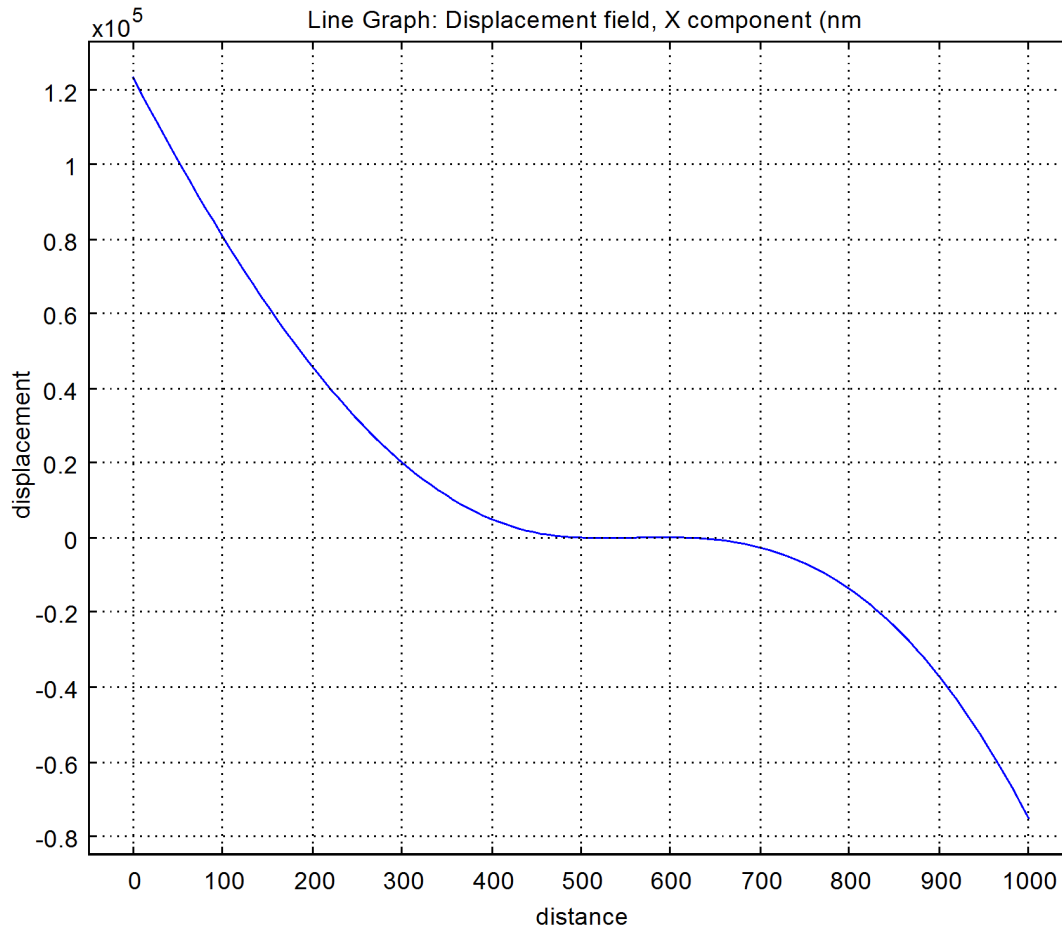
Acceleration: 100g

Surface: Total displacement (nm) Surface Deformation: Displacement field



Acceleration: 200g

# Displacement along the spring

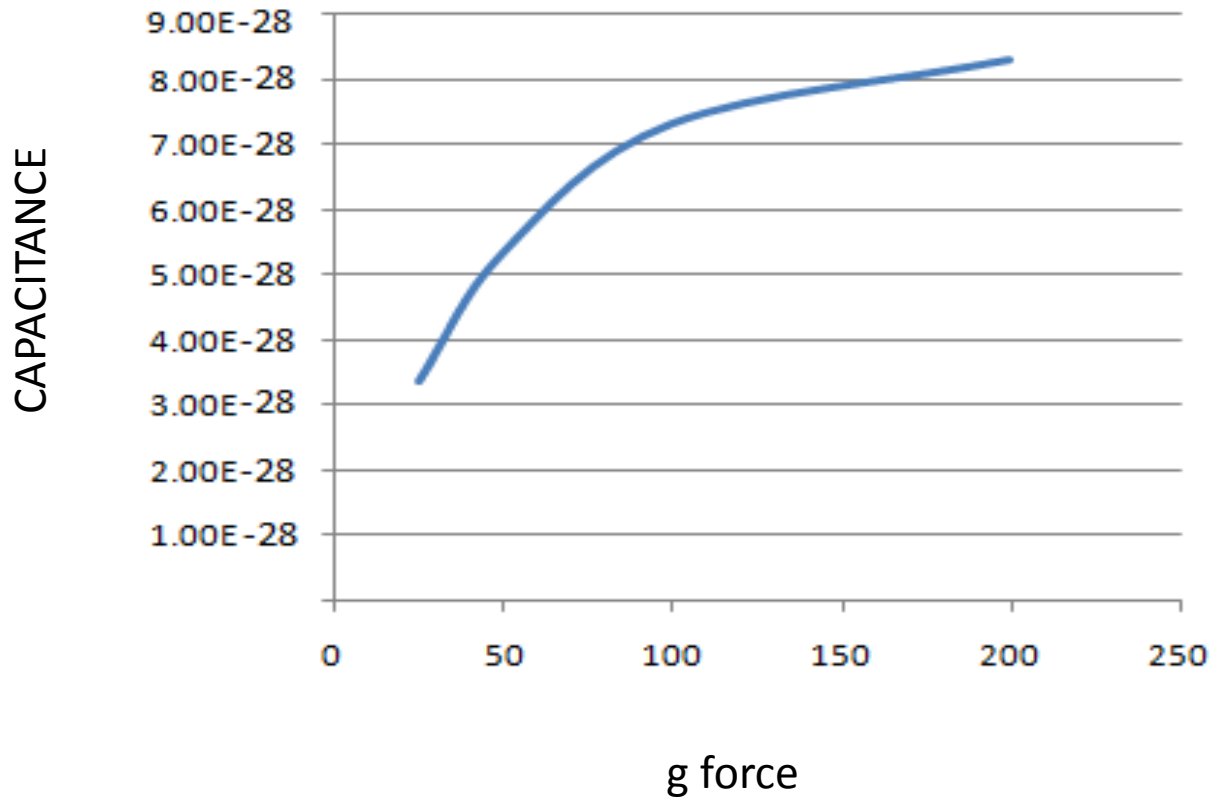


Displacement along the spring length

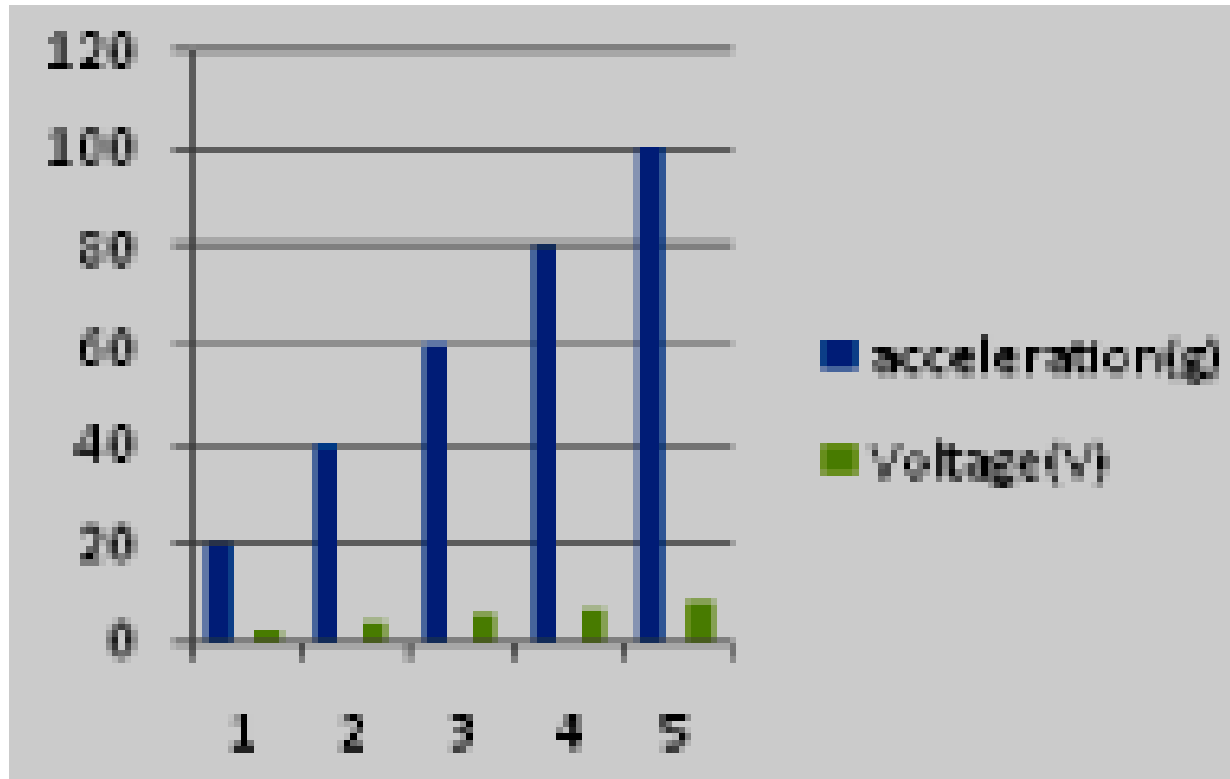




# Capacitance Variation



# Variation of acceleration with voltage



Relation between acceleration and voltage

## Conclusion

- Accelerometers for airbag deployment applications designed
- Capacitance Studies done
- Nano dimensions

## Future Work

Stability studies  
Fabricating the accelerometer





## References

- [1] Ninia Sejersen Almind, Simon Hedegaard Brodersen "MEMS PZT Based Accelerometer: Design, Fabrication and Characterization" Thesis submitted to University of Denmark (2007).
- [2] Wenjing ZHAO, Limei XU "Design of a Capacitive SOI" Micromachined Accelerometer, sensors and transducers(2009)
- [3] Rajib Ul Alam Uzzal, Ion Stiharu, and Waiz Ahmed "Design and Analysis of MEMS based Accelerometer for Automatic Detection of Railway Wheel Flat" World Academy of Science, Engineering and Technology (2009)
- [4] Stephen D. Senturia, "Microsystem Design", Kluwer Academic Publishers (2009)





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